

TRANSMITTAL OF INFORMATION DISCLOSURE STATEMENT**(Under 37 CFR 1.97(b) or 1.97(c))**

Docket No.

SKL008C2

In Re Application Of: **Shunji Hayashi**

APR 08 2004

Serial No.

10/712,100

Filing Date

November 14, 2003

Examiner

Unknown

Group Art Unit

2825

Title: **METHOD AND SYSTEM FOR MANAGING SEMICONDUCTOR MANUFACTURING EQUIPMENT**

Address to:

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

37 CFR 1.97(b)

1. ☒ The Information Disclosure Statement submitted herewith is being filed within three months of the filing of a national application other than a continued prosecution application under 37 CFR 1.53(d); within three months of the date of entry of the national stage as set forth in 37 CFR 1.491 in an international application; before the mailing of a first Office Action on the merits, or before the mailing of a first Office Action after the filing of a request for continued examination under 37 CFR 1.114.

37 CFR 1.97(c)

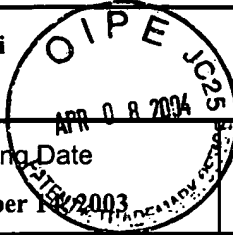
2. ☐ The Information Disclosure Statement submitted herewith is being filed after the period specified in 37 CFR 1.97(b), provided that the Information Disclosure Statement is filed before the mailing date of a Final Action under 37 CFR 1.113, a Notice of Allowance under 37 CFR 1.311, or an Action that otherwise closes prosecution in the application, and is accompanied by one of:
- ☐ the statement specified in 37 CFR 1.97(e);
- OR**
- ☐ the fee set forth in 37 CFR 1.17(p).

Note: The enclosed references were cited in copending U.S. Application Serial No. 10/125,403, and thus may be material to the prosecution of the present application.

TRANSMITTAL OF INFORMATION DISCLOSURE STATEMENT
(Under 37 CFR 1.97(b) or 1.97(c))

Docket No.
SKI.008C2

In Re Application: Shunji Hayashi



Serial No.
10/712,100

Filing Date
November 19, 2003

Examiner
Unknown

Group Art Unit
2825

METHOD AND SYSTEM FOR MANAGING SEMICONDUCTOR MANUFACTURING

Payment of Fee

(Only complete if Applicant elects to pay the fee set forth in 37 CFR 1.17(p))

- ☐ A check in the amount of _____ is attached.
- ☒ The Director is hereby authorized to charge and credit Deposit Account No. **50-0238** as described below.
- ☐ Charge the amount of _____
- ☒ Credit any overpayment.
- ☒ Charge any additional fee required.

Certificate of Transmission by Facsimile*

I certify that this document and authorization to charge deposit account is being facsimile transmitted to the United States Patent and Trademark Office (F:

(Date)

Signature

Typed or Printed Name of Person Signing Certificate

Certificate of Mailing by First Class Mail

I certify that this document and fee is being deposited on _____ with the U.S. Postal Service as first class mail under 37 C.F.R. 1.8 and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

Signature of Person Mailing Correspondence

Typed or Printed Name of Person Mailing Certificate

*This certificate may only be used if paying by deposit account.

Signature

Dated: April 8, 2004

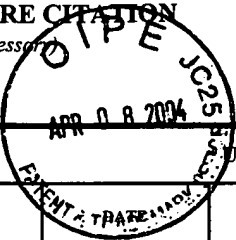
ANDREW J. TELESZ, JR.
REG. NO. 33,581

VOLENTINE FRANCOS, P.L.L.C.
12200 SUNRISE VALLEY DRIVE, SUITE 150
RESTON, VA 20191

TEL. NO. (703) 715-0870

CC:

INFORMATION DISCLOSURE CITATION <i>(Use several sheets if necessary)</i>				Docket Number (Optional) SKI.008C2		Application Number 10/712,100	
				Applicant(s) Shunji Hayashi			
				Filing Date November 14, 2003		Group Art Unit 2825	



U.S. PATENT DOCUMENTS							
*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	A	6,438,440	08/2002	Hayashi			
	B	6,117,601	09/2000	Kanazawa et al.			
	C	2002/0188367	12/2002	Hayashi			
	D	5,392,364	02/1995	Yokoyama et al.			

FOREIGN PATENT DOCUMENTS								
	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
							YES	NO
	E	2000-114130	04/21/2000	Japan				
	F	2001-223885 A	08/2001	Japan				
	G	2000-275757 A	10/2000	Japan				
	H	10124766 A	05/1998	Japan				

OTHER DOCUMENTS <i>(Including Author, Title, Date, Pertinent Pages, Etc.)</i>		

EXAMINER	DATE CONSIDERED
----------	-----------------

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Re PATENT APPLICATION of

Shunji Hayashi

Examiner: Unknown

Serial No.: 10/712,100

Attorney Docket No. SKI.008C2

Filed: November 14, 2003

Art Unit No.: 2825

For: METHOD AND SYSTEM FOR MANAGING SEMICONDUCTOR
MANUFACTURING EQUIPMENT

LETTER OF RELATED APPLICATION

U.S. Patent and Trademark Office
2011 South Clark Place
Crystal Plaza Two, Lobby, Room 1B03
Alexandria, VA 22202

Date: April 8, 2004

Sir:

The Examiner is hereby advised of co-pending U.S. Application Serial No. 10/125,403. The subject matter contained in this co-pending U.S. Application Serial No. 10/125,403 is related to the present application and thus may be material to the prosecution of this instant application.

This application is not to be construed as prior art. By bringing this application to the attention of the Examiner, Applicant does NOT waive the confidentiality provisions of 35 U.S.C. 122.

Respectfully submitted,

VOLENTINE FRANCOS, P.L.L.C.

Andrew J. Telesz, Jr.
Registration No. 33,581

12200 Sunrise Valley Drive, Suite 150
Reston, VA 20191
Tel. (703) 715-0870
Fax. (703) 715-0877